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Date:	August 13, 2004		
To:	US Patent & Trademark Office Fax: 703-872-9306		
From:	David E. Steuber Tel: 408/982-8201 Fax: 408/982-8210		
Pages	9 (including cover sheet)		
Inventors:	William R. Entley et al.		
Title:	In Situ Plasma Process To Remove Fluorine Residues From The Interior Surfaces Of A CVD Reactor		
Application	10/003,908	Confirmation	7739
Examiner:	Anita Karen Alanko		

Enclosed for filing in the above-identified application are the following:

**Transmittal Letter (1 page); and
Amendment After Final (7 pages)**

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TRANSMITTAL FORM

(to be used for all correspondence after initial filing)

Total Number Of Pages In This Submission

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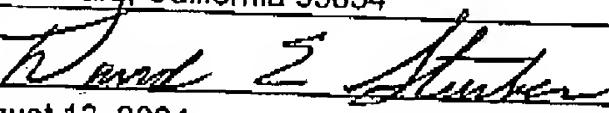
Application Number	10/003,908
Filing Date	11/1/2001
First Named Inventor	William R. Entley
Group Art Unit	1765
Examiner Name	Anita Karen Alanko
Attorney Docket No.	NVS013 US

ENCLOSURES (check all that apply)

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<input checked="" type="checkbox"/> After Final (7 pages)	<input type="checkbox"/> Petition	<input type="checkbox"/> Proprietary Information
<input type="checkbox"/> Affidavits/declarations	<input type="checkbox"/> Petition to Convert to a Provisional Application	<input type="checkbox"/> Status Letter
<input type="checkbox"/> Extension of Time Request	<input type="checkbox"/> Power of Attorney, Revocation of Previous Powers; And Statement Under 37 CFR 3.73(b)	<input type="checkbox"/> Other Enclosure(s) (please identify below):
<input type="checkbox"/> Express Abandonment Request	<input type="checkbox"/> Terminal Disclaimer	
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<input type="checkbox"/> Response to Missing Parts under 37 CFR 1.52 or 1.53		

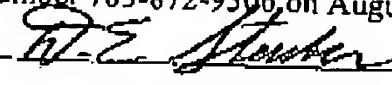
Remarks

SIGNATURE OF APPLICANT, ATTORNEY OR AGENT

Firm or Individual Name	David E. Steuber (Reg. No. 25,557) Silicon Valley Patent Group LLP 2350 Mission College Boulevard, Suite 360 Santa Clara, California 95054
Signature	
Date	August 13, 2004

CERTIFICATE OF FACSIMILE TRANSMISSION

I hereby certify that this correspondence is being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number 703-872-9306 on August 13, 2004.

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Attorney for Applicant(s)

Date of Signature

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Tech. Center/ Art Unit	1765	Examiner	Anita Karen Alanko
Title:	In Situ Plasma Process To Remove Fluorine Residues From The Interior Surfaces Of A CVD Reactor		
Docket No.:	NVS013 US	Customer No.:	34036

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Santa Clara, California
August 13, 2004

AMENDMENT AFTER FINAL ACTION

Dear Sir:

In response to Office Action dated May 19, 2004, please amend the above-identified application as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.